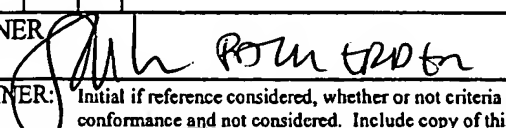


FORM PTO-1449 (REV. 7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 854063.552D1	APPLICATION NO.		
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANTS Gabriele Barlocchi et al.			
				FILING DATE September 18, 2003		GROUP ART UNIT	
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	AA	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
Pg	AA	4,579,621	04/01/86	Hine	156	612	
Pg	AB	4,993,143	02/19/91	Sidner et al.	29	621.1	
Pg	AC	5,659,138	08/19/97	Iwata et al.	73	514.33	
Pg	AD	5,883,420	03/16/99	Mirza et al.	257	419	
Pg	AE	5,926,721	07/20/99	Hong et al.	438	413	
Pg	AF	5,889,872	03/30/99	Sooriakumar et al.	381	174	
Pg	AG	6,093,330	07/25/00	Chong et al.	216	2	
Pg	AH	6,180,480	01/30/01	Economikos et al.	438	386	
Pg	AI	6,307,247	10/23/01	Davies	257	522	
	AJ						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION		
					YES	NO	
Pg	AK	JP4114470	04/15/92	Japan (+abstract)			
Pg	AL	JP9082983	03/28/97	Japan			
	AM						
	AN						
	AO						
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
Pg	AP	Tabata, Osamu et al., "Anisotropic etching of silicon TMAH solutions", Sensors and Actuators, July 1992. Pages 51-57.					
Pg	AQ	Kovacs, Gregory T. A. et al., "Bulk Micromachining of Silicon", IEEE, August 1998. Vo. 86, No. 8, Pages 1536-1551.					
	AR						
EXAMINER				DATE CONSIDERED			
				03/14/05			
* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).							